

~~D~~  
processing apparatus, of holding and transporting said one or more wafers, and of  
~~transferring~~ said one or more wafers, via said duct, to said insertion portion of another wafer  
processing apparatus.

B2 [2] Please replace claim 12 with the following new claim 12 (APPENDIX 2):

12. (twice amended) A conveyance system in accordance with claim 10, wherein said position detecting element comprises a plurality of mobile element detecting sensors placed along said guide path, and said mobile element detecting sensors are placed at regular distance intervals throughout the ~~guide path~~ or placed at narrower intervals near the wafer processing apparatuses than along midways between adjacent two wafer processing apparatuses.

[3] Please replace claim 13 with the following new claim 13 (APPENDIX 3):

13. (twice amended) A conveyance system in accordance with claim 1, wherein the degree of air purity in said chamber is higher than the degree of purity outside said chamber.